

**MD.101.**

**Title**

**Deformation vacuum gauge**

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**DECISION on registration of industrial designs  
Vacuumetru**

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To improve the accuracy of low pressure measurements, a  
VD-10 tensoresistive vacuum gauge sample has been  
developed and constructed; the gauge includes a measuring  
unit and a transducer, the sensitive element of which is a  
silicon crystal in the middle part of which a thin membrane  
with tensoresistors placed on the outer surface is formed.

**Description**

**EN**

To decrease the dependence on the ambient temperature, a  
circuit consisting of a transistor and resistors is formed on  
the crystal; the circuit provides power to the bridge circuit  
with a temperature-dependent voltage to compensate for the  
drift. In addition, temperature fluctuations are recorded by  
the measuring unit for additional software correction.

**Class no.**

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